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In the Claims:

Please cancel claim 19 without prejudice and amend the claims as follows:

1. A charged particle beam device, comprising:
 a charged particle emitter (2) for emitting a primary charged particle beam (12);
 a deflection system, comprising three deflection stages (14; 21; 72);
wherein ~~whereby~~ the deflection system is arranged for deflecting the primary charged particle beam and specimen-released charged particles along a first or a second beam path (12a, 12b);
at least two detection units (16; 44), each associated with one of the first or second beam path, so that the deflection system is adapted to switch between the at least the two detection units; and
wherein ~~whereby~~ one of the three deflection stages (14) is closer to a specimen stage (6) than the two detection units (16).
2. The charged particle beam device according to claim 1, further comprising:
 an aperture unit (15; 112) for shaping the charged particle beam.
3. The charged particle beam device according to claim 2, wherein ~~whereby~~ the aperture unit (15; 41; 112) is a multi-aperture unit (15; 41) having at least comprising two apertures (51; 42; 43); and wherein ~~whereby~~ each aperture of the two apertures is associated with one of the first or second beam path so that the deflection system is adapted to switch between the two apertures and a corresponding detection unit of the two detection units.
4. The charged particle beam device according to claim 1 ~~any of the preceding claims~~, wherein the deflection system comprises ~~comprising~~ six dipole deflectors (14; 21; 72); and ~~whereby the deflection system~~ is arranged for deflecting the primary charged particle beam and the specimen-released charged particles in two dimensions (x,y).

5. The charged particle beam device according to claim 4, wherein ~~whereby~~ each of the three deflection stages comprises two of the six dipole deflectors.
6. The charged particle beam device according to claim 1 ~~any of the preceding claims~~, wherein ~~whereby~~ each of the three deflection stages comprises a magnetic deflection component.
7. The charged particle beam device according to claim 1 ~~any of the preceding claims~~, wherein ~~whereby~~ the two detection units are similar and the two apertures are similar.
8. The charged particle beam device according to ~~any of claim 3~~ claims 2 to 6, ~~wherein whereby the two detection units (16, 44) are different and the two apertures (42, 43) are different.~~
9. The charged particle beam device according to claim 1 ~~any of the preceding claims~~, comprising six detection units ~~(16, 44)~~ and six apertures ~~(42, 43)~~, wherein whereby three of the six detection units ~~(16, 44)~~ and three of the six apertures ~~(43, 43)~~ are similar.
10. The charged particle beam device according to claim 1 ~~any of the preceding claims~~, wherein whereby a primary beam deflection angle (18a) and a specimen-released charged particles deflection angle ~~(18b)~~ are different.
11. The charged particle beam device according to claim 1 ~~any of the preceding claims~~, further comprising a mirror unit ~~(32)~~.
12. The charged particle beam device according to any of claim ~~claims 1 to 8~~, wherein ~~whereby~~ a primary beam deflection angle ~~(88)~~ and a specimen-released charged particles deflection angle ~~(88)~~ are substantially the same.

13. The charged particle beam device according to claim 3 ~~any of the preceding claims, wherein whereby~~ the apertures are arranged in a first sector area (96) and the detection units are arranged in a second sector area (95), and wherein ~~whereby~~ the first and the second sector areas do not overlap.

14. The charged particle beam device according to claim 1 ~~any of the preceding claims, wherein whereby~~ the three deflection stages are arranged symmetrically to a plane substantially orthogonal to the optical axis (11).

15. A m~~M~~ethod of imaging a specimen, comprising the following steps:

providing a primary charged particle beam;

deflecting the primary charged particle beam away from an optical axis using a first deflection stage of a deflection system;

deflecting the primary charged particle beam towards the optical axis using a second deflection stage of a deflection system;

redirecting the primary charged particle beam to travel substantially along the optical axis using a third deflection stage;

focusing the primary charged particle beam on a specimen such that the specimen releases charged particles; and

deflecting the specimen-released charged particles, whereby the third deflection stage is controlled such that one detection unit of two detection units is selected.

16. The m~~M~~ethod of imaging a specimen according to claim 15, wherein ~~whereby~~ the first and the second deflection stages are controlled such that an aperture of a multi-aperture unit is selected, wherein the aperture correspondsing to a detection unit of the two detection units, ~~is selected~~.

17. The m~~M~~ethod of imaging a specimen according to claim 15 ~~any of claims 15 to 16, wherein whereby~~ the method steps of deflectingon the primary charged particle beam and the specimen-released charged particles are conducted in two dimensions.

18. A m~~M~~ultiple charged particle device, comprising:

a charged particle emitting unit (102) for emitting a plurality of primary charged particle beams (12);

a plurality of deflection systems, each comprising at least three deflection stages (14; 21; 72), wherein ~~whereby~~ the deflection system is arranged for deflecting the plurality of primary charged particle beams and a plurality of specimen-released charged particles along a plurality of at least a first or a second beam paths (12a, 12b);

a plurality of at least two detection units (16; 44), each of the plurality of the at least two detection units associated with one of the plurality of primary beams and each of the at least two detection units associated with one of the at least first or second beam path so that the deflection systems are adapted to switch between the at least two detection units; and a multi-lens unit for focusing the plurality of charged particle beams.

19. (Cancelled)

20. A charged particle beam device, comprising:

a charged particle emitter (2) for emitting a primary charged particle beam (12);

a deflection system, comprising three deflection stages (14; 21; 72), wherein ~~whereby~~ the deflection system is arranged for deflecting the primary charged particle beam and specimen-released charged particles along a first or a second beam path (12a, 12b);

two detection units (16), each associated with one of the first or second beam path[,] so that the deflection system is adapted to switch between the two detection units; [and]

wherein ~~whereby~~ one of the three deflection stages (14) is closer to a specimen stage (6) than the two detection units (16; 44);

wherein the charged particle beam device further comprises ~~comprising~~ an aperture unit (15; 41) for shaping the charged particle beam, wherein ~~whereby~~ the aperture unit (15; 41) is a multi-aperture unit (15; 41) comprising two apertures (51; 42, 43); and

wherein ~~whereby~~ each aperture of the two apertures is associated with one of the first or second beam path so that the deflection system is adapted to switch

between the two apertures and the corresponding detection unit of the two detection units.